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E2 E1

E3

E4 E3

Effect of the Electrode Angle on the Optical Properties of Electrostatic Immersion Lens

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ABSTRACT

Two models of an electrostatic immersion lenses of double electrodes have been designed of equal diameter and pole thickness, at different distances between their

electrodes for the upper and lower parts. Each model includes two lenses according to its electrode angle that varied. The effect of the variation of the single electrode angle was studied for each lens on the optical properties at a constant voltage ratio. An optimum electrode angle has been chosen for the lenses one with a lowest spherical and chromatic aberration coefficients in order to compared its optical properties at different voltages ratio at zero magnification condition. It was found that the lenses E1 and E3 are better than E2 and E4 in the two models. Moreover, it was found that E3 has an optimum optical performance within the two models. The results of the optical properties of the electrostatic lenses in the present work have been compared with those of the published results. A great improvement in the optical performance of the considered lenses has been found.

Keywords: Electrostatic lenses, immersion lenses, double electrodes lenses, electrode angle.

(Electron Spectrometer)

(Sise *et al.*, 2004)

(Al-Khashab and Al-Abdullah, 2013) (Al-Khashab and Al-Abdullah, 2012)

(Al-Khashab and Al-Abdullah, 2013)

(SEM)

(Al-Khashab and Ahmed, 2012) (Abd-Hujazie, 2006) Gemini

Two-element electrostatic immersion)

(lenses

(Shemesh, 2005)

(Mulvey and Wallington, 1973)

.....

Read 1969

(Read, 1969)

(Least-squares collocation method)

Szilagyi

1987

1997

Jackson

(Szilagyi *et al.*, 1987)

(FEM)

(Jackson, 1997)

Al-

Al-Jumayli Shamma

(Al-Jumayli, 2010) (Al-Shamma, 2007)

(Outer)

(Inner)

(Quasistatic approximation)

(Hawkes and Kasper, 1996)

:

$$\nabla^2 V = 0 \quad \dots\dots\dots(1)$$

(θ) (r, θ, z)
 First order finite element) . $V(r, z)$
 Munro (method
1975

(Magnetic and electrostatic deflectors)
.(Lencová, 2002)

(Z)
 :(Hawkes, 1972)

$$r''(Z) + \frac{V'}{2V} r'(Z) + \frac{V''}{4V} r = 0 \quad \dots\dots\dots(2)$$

r , V'' , V'
 r'
 .(Fourth order Range – Kutte method) (-)
 (4) (3) (C_{co}) (C_{so})

:(Szilagyi and Szep, 1987)

$$C_{so} = \frac{1}{16V_o^{1/2} r_o^{14}} \int_{z_o}^{z_i} \left\{ \left[\frac{5}{4} \left(\frac{V''}{V} \right)^2 + \frac{5}{24} \left(\frac{V'}{V} \right)^4 \right] r^3 + \frac{14}{3} \left(\frac{V'}{V} \right)^4 r' r^3 - \frac{3}{2} \left(\frac{V'}{V} \right)^2 r'^2 r^2 \right\} V^{\frac{1}{2}} dz \quad \dots\dots(3)$$

$$C_{co} = \frac{V_o^{1/2}}{r_o^{12}} \int_{z_o}^{z_i} \left(\frac{V'}{2V} r' r + \frac{V''}{4V} r^2 \right) V^{\frac{-1}{2}} dz \quad \dots\dots(4)$$

V_o Z_o
(C_{ci}) (C_{si})
 r_i^{14} $V_i^{1/2}$ r_o^{14} $V_o^{1/2}$
 . (Simpson's rule)

(1)

.....

E1, E2,) (Meshes)

(D=3 mm) (E3 & E4)

E2 E1 .s d (t=5 mm)

[$\theta=(0^\circ, 10^\circ, 20^\circ, 30^\circ, 40^\circ, 50^\circ)$] (s=10 mm)

(d=15 mm) E4 E3

(1)

(Munro, 1975) 1975 Munro (E11)

(2) (Abd-Hujazi, 2006)

(V=1000 volt) (V=0.0 volt)

(Z=-1 mm) (Z=-10 mm) (2a)

(E_z) (Convergent region)

(Divergent region) (Convergent power)

(Z=10 mm) (Z=2 mm)

(E_z)

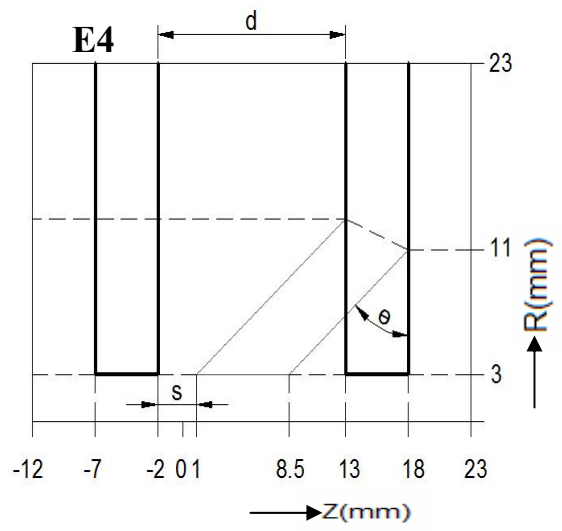
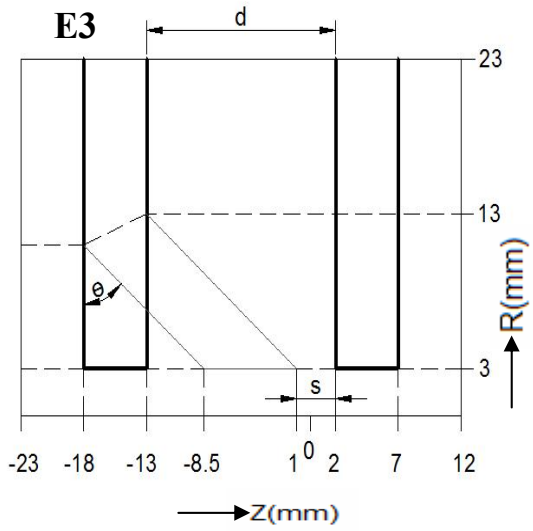
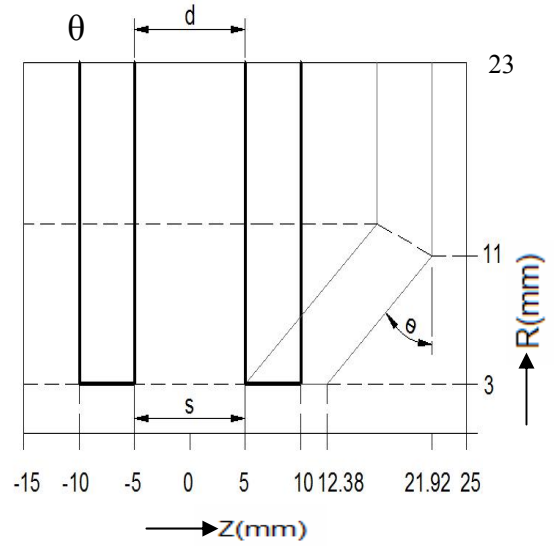
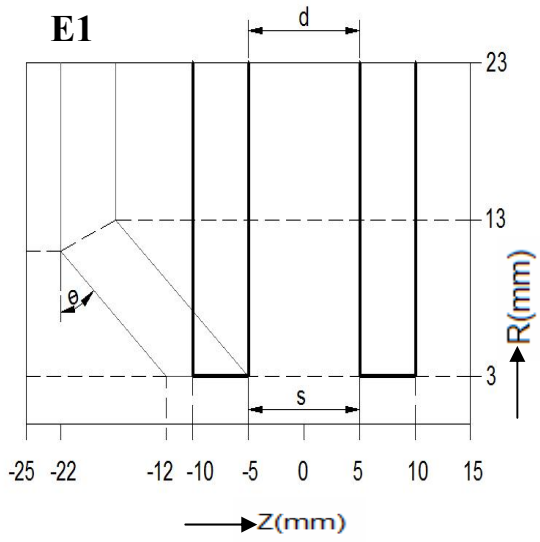
E1 E2 (Grivet, 1972)

(Lencová, 1997)

E4 E3 (2b)

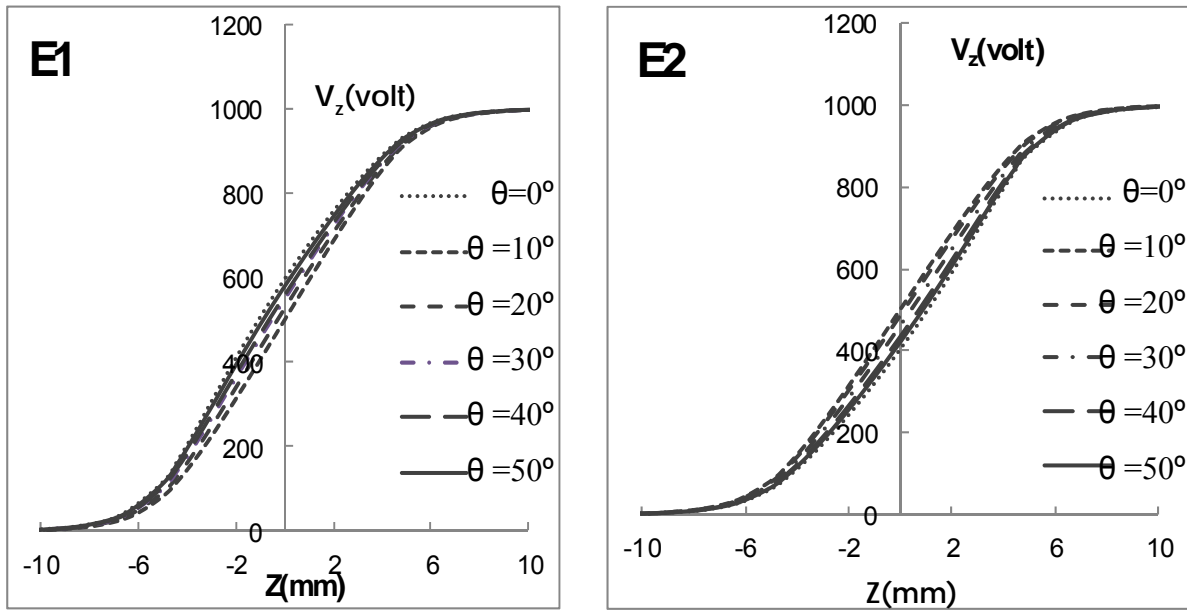
(3) .1975 Munro (E31)

($V_i/V_o=50$) ($\theta=50^\circ$)

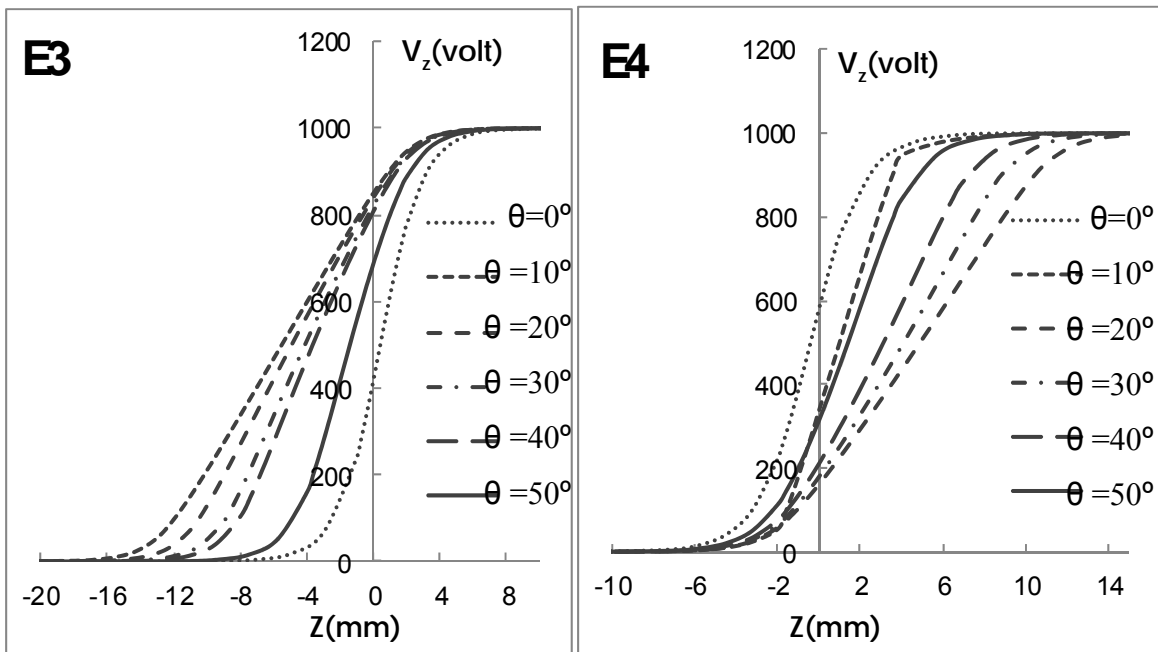


:1

.(E1, E2, E3 & E4)



(a)



(b)

(E1, E2, E3 & E4)

:2

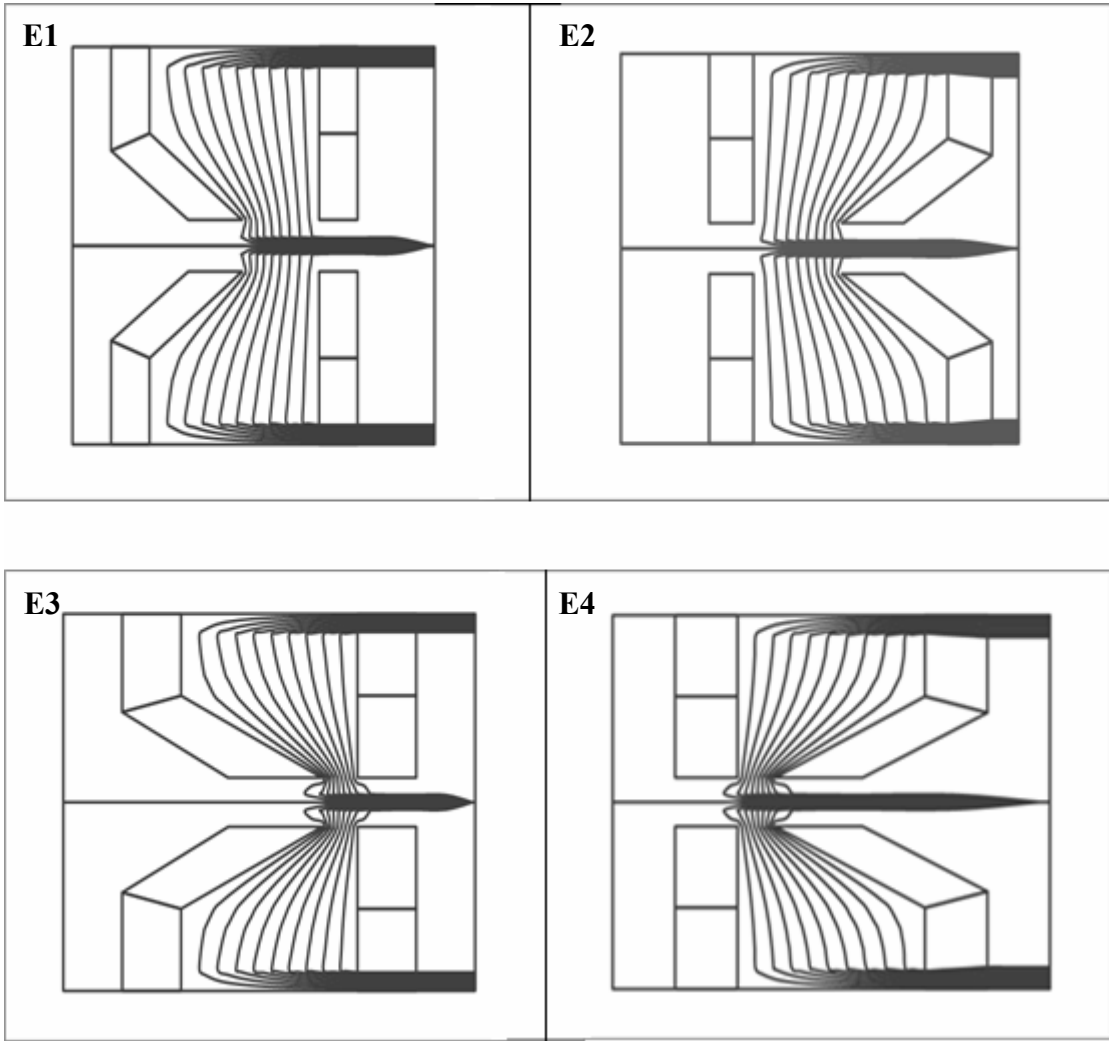
E3

(4a ,4b) (4) (3)

($V_i/V_o=50$)

E4, E3

E2,E1

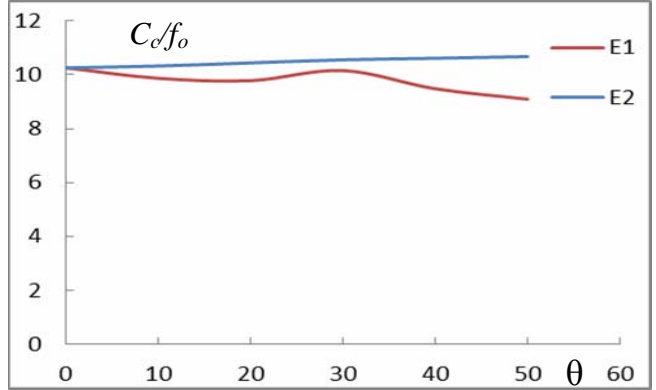
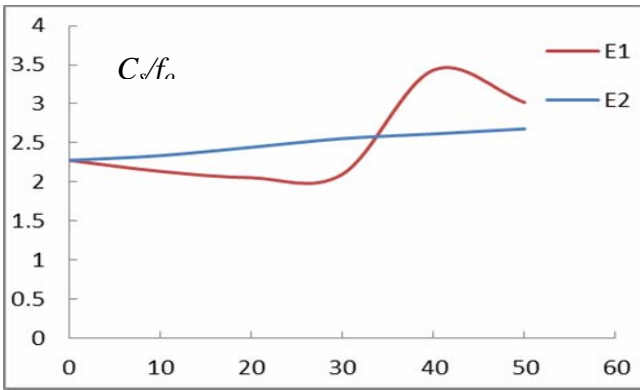
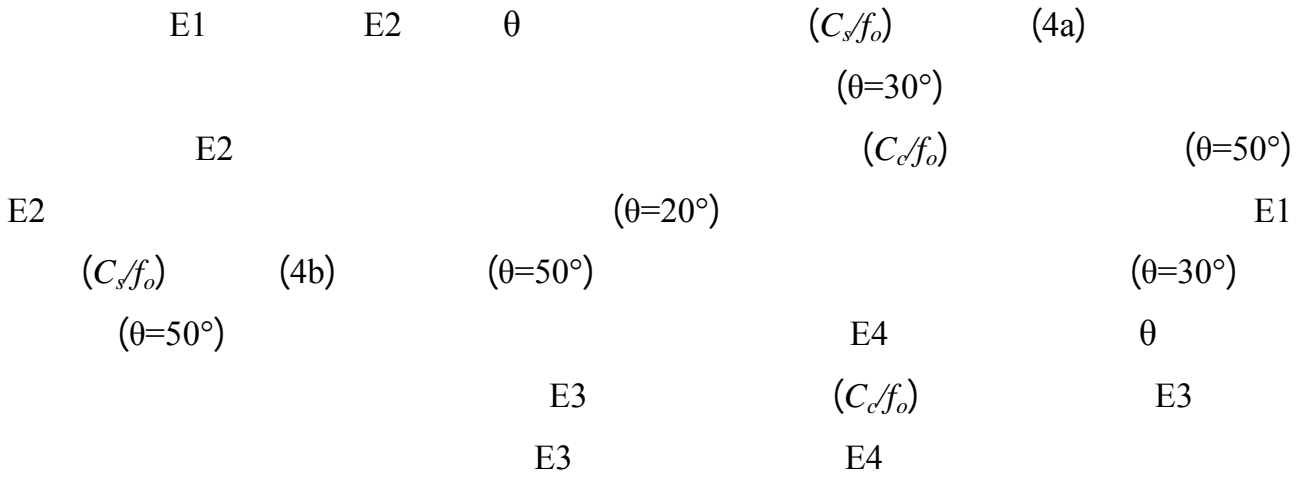


(E1, E2, E3 & E4)

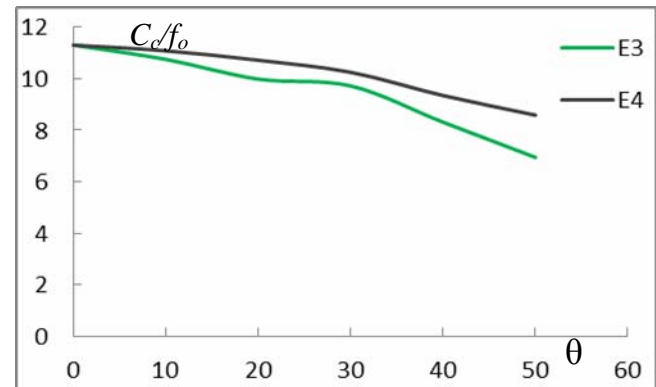
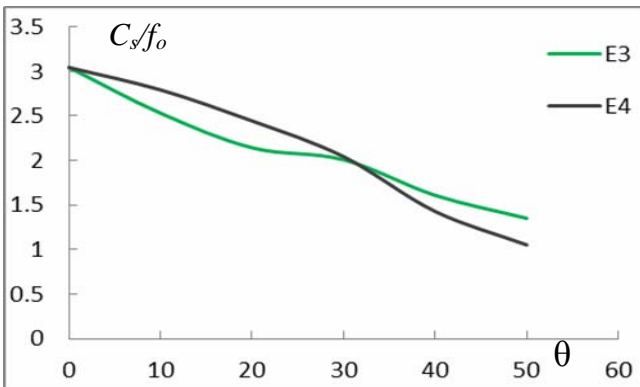
:3

($V_i/V_o=50$) ($\theta=50^\circ$)

.....



(a)



(b)

(C_d/f_o) (C_s/f_o)
 $(V_i/V_o=50)$

:4

$(\theta=50^\circ)$

(5)

(C_s/f_o)

(V_i/V_o)

E2

E2

$(V_i/V_o=150)$

$(V_i/V_o=50)$

E3

(C_c/f_o)

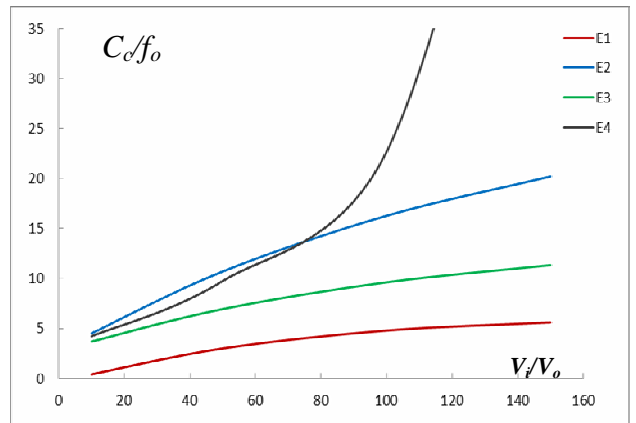
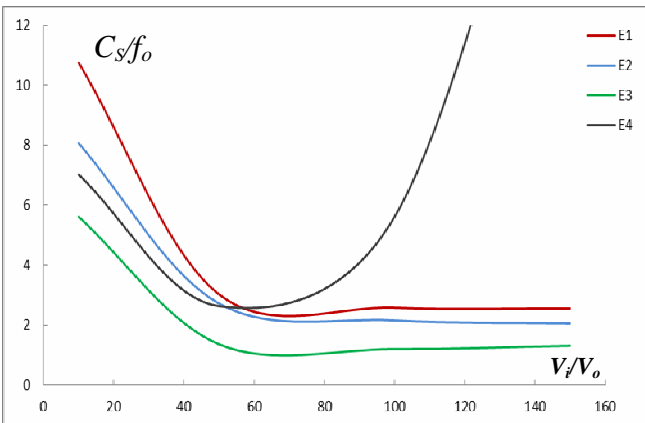
E1

.E3

E3

(1)

$(V_i/V_o=50)$



(C_c/f_o) (C_s/f_o)
 $(\theta=50^\circ)$

$(V_i/V_o=50)$

:5

E1, E2,)

:1

($V_i/V_o=50$)

(E3& E4

Lens θ	E1($V_i/V_o=50$)		E2($V_i/V_o=50$)		E3 ($V_i/V_o=50$)		E4($V_i/V_o=50$)	
	(C_s/f_o)	(C_c/f_o)	(C_s/f_o)	(C_c/f_o)	(C_s/f_o)	(C_c/f_o)	(C_s/f_o)	(C_c/f_o)
0°	2.279	10.256	2.278	10.254	3.044	11.309	3.044	11.309
10°	2.137	9.869	2.338	10.323	2.532	10.755	2.793	11.087
20°	2.055	9.780	2.445	10.437	2.144	9.989	2.445	10.724
30°	2.099	10.155	2.556	10.552	2.009	9.724	2.044	10.253
40°	3.432	9.481	2.616	10.610	1.610	8.318	1.429	9.350
50°	3.018	9.092	2.680	10.670	1.352	6.948	1.054	8.591

($\theta=50^\circ$)

(E3)

.(2)

($V_i/V_o=150$)

($V_i/V_o=50$)

E3

($V_i/V_o=10$)

($\theta=50^\circ$)

(Al-Meshhdany, 2002) (Munro, 1975)

(3)

(Al-Shamma, 2007)

(E1,E2,E3&E4)

:2

($\theta=50^\circ$)

Lens (V_i/V_o)	E1 ($\theta=50^\circ$)		E2 ($\theta=50^\circ$)		E3 ($\theta=50^\circ$)		E4 ($\theta=50^\circ$)	
	(C_s/f_o)	(C_c/f_o)	(C_s/f_o)	(C_c/f_o)	(C_s/f_o)	(C_c/f_o)	(C_s/f_o)	(C_c/f_o)
10	10.747	0.423	8.059	4.517	5.606	3.700	7.014	4.232
50	3.018	3.012	2.710	10.709	1.352	6.948	2.625	9.756
100	2.571	4.798	2.148	16.272	1.192	9.623	5.604	22.700
150	2.547	5.612	2.046	20.204	1.302	11.334	22.577	75.926

:3

 $(V_i/V_o=10)$

(Ref.)	(C_s/f_o)	(C_c/f_o)
(Lens E3)	5.606	3.700
(Munro, 1975)	11.81	4.82
(Al-Meshhdany, 2002)	23.6	7.3
(Al-Shamma, 2007)	4.85	4.20

.1

.($\theta=50^\circ$)

.2

.(E2, E4)

(E1, E3)

.3

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